

IN THE SPECIFICATION:

Page 10, please amend the paragraph beginning at line 26 as follows:

The foregoing objects are achieved by the diagnosis apparatus of the semiconductor manufacturing apparatus being connected with means of recording the information of operations to be executed by the semiconductor manufacturing apparatus for processing raw materials and forming a semiconductor as predetermined data through a communicating facility arrangement and having means of displaying the result simulated by the means of operating the operation of the semiconductor manufacturing apparatus through the use of the data for simulating the operation.

Page 11, please amend the paragraph beginning at lines 9 and 22 as follows:

Further, the foregoing objects are achieved by a program for a semiconductor manufacturing apparatus having a receiving function of receiving from a supplier of supplying the information of the operations to be executed by the semiconductor manufacturing apparatus for processing raw materials and forming a semiconductor as the predetermined data the data through the communicating facility arrangement, a displaying function of displaying the simulated result of the means of operating the operations of the semiconductor manufacturing apparatus through the use of the data for simulating the operation, and a transmitting function of transmitting the result to the supplier.

Moreover, the foregoing objects are achieved by an operating system for the semiconductor manufacturing apparatus having means of receiving from a supplier of supplying the information of the operations to be executed by the semiconductor manufacturing apparatus for processing raw materials and forming a semiconductor as the predetermined data the data through the communicating facility arrangement and means of displaying the result simulated by the means of operating the

operations of the semiconductor manufacturing apparatus for simulating the operations and providing the diagnosis result of the semiconductor manufacturing apparatus based on the result simulated on the received data in response to the request given from the user of the semiconductor manufacturing apparatus.

Page 32, please amend the paragraph beginning at line 6 as follows:

In this case, the communication security facility arrangement is required to be provided so that the information of the content included in the log file of the apparatus is not made open to the third party. Between the wide area communication network 112 and the in-site communication arrangement 111c of the apparatus user or the in-office communication arrangement 111d of the apparatus supplier is located means of restricting the communication between the outside and the inside of the factory 110 or the office 106 such as a firewall 109. Since the wide area communication network like the internet is a public network, the security has to be secured by the VPN (Virtual Private Network), for example. Instead, the information itself may be encrypted by means of the public key encrypting system or the common key encrypting system.

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Page 36, please amend the paragraph beginning at line 16 as follows:

The flow of this operating system is recorded in the storage unit provided in the apparatus in the predetermined data format as the operator 301 of the apparatus starts the apparatus. The resulting data is made to be an apparatus log file. Further, as noted above, this operation information is communicated with the terminal or the storage unit of the administrator 304 of the apparatus located in a remote place (like an office) from the apparatus itself through the communication facility arrangement and then is recorded therein. The information may be recorded in the terminal or the

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storage unit located in a residence or an office of the apparatus supplier 306 or the information relay 305 or the information server 309.

Page 37, please amend the paragraphs beginning at lines 2 and 9 as follows:

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While the apparatus operator 303 is operating the apparatus, if an abnormality like an error or an unfavorable condition takes place, this occurrence is notified to the apparatus administrator 304, the apparatus information server 309, and the apparatus supplier 306 (apparatus information supplier source 310) through the communication facility arrangement.

When the abnormality is reported, the apparatus administrator 304, the apparatus supplier 306 or the apparatus information supplier 310 may obtain the apparatus operation information (apparatus log file) from each recording place through the communication facility arrangement or the like. When the operation record is obtained, the apparatus supplier 306 and the information source 310 operate to determine the cause of the abnormality or the state of the apparatus through the use of the foregoing remote diagnosing means and then present the measures against the cause based on the determined result. The presented measures are supplied to the information server 309 or the apparatus administrator 304 or directly sent to the apparatus operator 303. The use of the measures makes it possible for the apparatus administrator 304, the operator 303 or the apparatus supplier to directly repair or adjust the apparatus. Upon termination of it, the information on the cause and the measures composed as the predetermined data by corresponding the cause with the measures on the side of the apparatus operator 303 is recorded in the recording unit or the like provided in the apparatus, for example. The information on the cause and the measures is transmitted to the apparatus administrator 304, the apparatus information server 309 and the

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apparatus supplier 306 (apparatus information source 310) and then is recorded therein.
